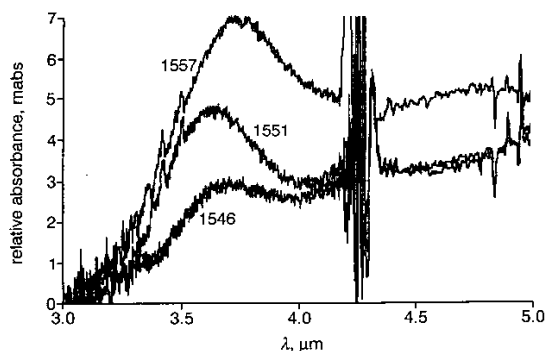
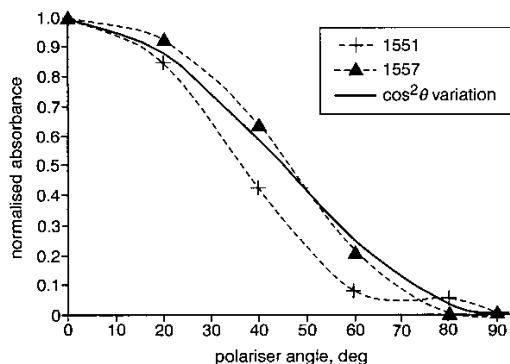


profile of 1557. Modelling of the quantum well subband energy levels was carried out using the envelope function approximation in which the energy states are described using a three-band Kane  $k \cdot p$  approximation that takes into account the effect of band nonparabolicity and strain. We used this model to design structures each with an  $n = 1$  to  $n = 2$  transition at about  $3.6 \mu\text{m}$  and to ascertain that all the samples have the same number of states in the well (three).



**Fig. 2** Room temperature FTIR absorption spectrum of samples 1546, 1551, and 1557 at Brewster angle using  $p$ -polarised light. Curves are offset for clarity. Dip at  $4.25 \mu\text{m}$  is due to  $\text{CO}_2$  absorption in infrared beam path



**Fig. 3** Normalised  $n = 1$  to  $n = 2$  peak intensity against polariser angle,  $\theta$ , for samples 1551 and 1557

**Results:** The room temperature intersubband absorption was measured in a Bio-Rad FT-3000 Fourier transform infrared spectrometer with a ZnSe wire grid polariser. Since the polarisation selection rule allows only radiation with its electric field vector perpendicular to the plane of the QW to stimulate an intersubband transition [1], the samples were oriented at the Brewster angle. The absorption spectrum was then measured using light  $p$ -polarised with respect to the plane of incidence. Fig. 2 shows the  $n = 1$  to  $n = 2$  intersubband absorption for the three samples studied. As expected there is an increase in the magnitude of absorption with carrier concentration for the two GaAs well samples (1546 and 1551). Significantly increased absorption is observed for the stepped well sample (1557) compared to 1551, even though it has a lower sheet carrier density (see Table 1). To investigate further the increased absorption in the stepped DBQW, the angle of the polariser was varied from  $\theta = 0$  to  $90^\circ$  thus varying the fraction of  $p$ -polarised light in the incident beam. The normalised peak intensities for the stepped well (1557) and the higher-doped GaAs well (1551) are shown in Fig. 3. According to the selection rule for light induced intersubband transitions in QWs the absorption should decrease as  $\cos^2\theta$  under these conditions. The solid line in Fig. 3 indicates this theoretical curve. The stepped well shows a greater than  $\cos^2\theta$  dependence of the peak intensity whereas the square well peak intensity drops off much more rapidly with polariser angle. The enhanced absorption in the stepped well and the persistence of the absorption to greater polariser angles indicates a degree of relaxation of the selection rule forbidding normal incidence absorption. Since all the samples have three levels in the well and incorporation of the step is known to increase the oscillator strength of the normally forbidden  $n = 1$  to  $n = 3$  transition [6], the increase in the  $n = 1$  to  $n = 2$

transition in sample 1557 cannot be due to an increase in oscillator strength for this transition. It has previously been proposed that reduction in the well bandgap partially relaxes the electric field vector selection rule [8]. Alternatively the step itself may have a similar effect due to the contribution to the energy states from two different materials. Relaxation of the selection rule in a conventional stepped well has been theoretically analysed in [9]. (It is interesting to note that here we observe absorption enhancement despite the  $n = 1$  level not being confined with the InGaAs alone.)

**Conclusion:** We have demonstrated an enhancement in the strength of the  $n = 1$  to  $n = 2$  intersubband absorption in GaAs DBQWs by introduction of an InGaAs layer. This occurs despite an expected reduction in the oscillator strength for this transition due to other normally forbidden transitions becoming allowed. The enhanced absorption is attributed to relaxation of the electric field vector selection rule.

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## References

- 1 LEVINE, B.F.: 'Quantum-well infrared photodetectors', *J. Appl. Phys.*, 1993, **74**, pp. R1–R81
- 2 LENCHYSHYN, L.C., LIU, H.C., BUCHANAN, M., and WASILEWSKI, Z.R.: 'Mid-wavelength infrared detection with  $\text{In}_x\text{Ga}_{1-x}\text{As}/\text{Al}_{0.45}\text{Ga}_{0.55}\text{As}$  multiple quantum well structures', *Semicond. Sci. Technol.*, 1995, **10**, pp. 45–48
- 3 LEVINE, B.F., GUNAPALA, S.D., and KÖPF, R.F.: 'Photovoltaic GaAs quantum well infrared detectors at  $4.2 \mu\text{m}$  using indirect  $\text{Al}_x\text{Ga}_{1-x}\text{As}$  barrier', *Appl. Phys. Lett.*, 1991, **58**, pp. 1551–1553
- 4 LIU, H.C., BUCHANAN, M., and WASILEWSKI, Z.R.: 'Short wavelength ( $1\text{--}4 \mu\text{m}$ ) infrared detectors using intersubband transitions in GaAs-based quantum wells', *Appl. Phys. Lett.*, 1998, **83**, pp. 6178–6181
- 5 NEU, G., CHEN, Y., DEPARIS, C., and MASSIES, J.: 'Improvement of the carrier confinement by double-barrier GaAs/AlAs/(Al,Ga)As quantum well structures', *Appl. Phys. Lett.*, 1991, **58**, pp. 2111–2113
- 6 MI, Y.J., WANG, K.L., KARUNASIRI, R.P.G., and YUH, P.F.: 'Observation of large oscillator strengths for both 1–2 and 1–3 intersubband transitions of step quantum well', *Appl. Phys. Lett.*, 1990, **56**, pp. 1046–1048
- 7 MISSOUS, M.: 'Stoichiometric low-temperature GaAs and AlGaAs: a reflection high-energy electron-diffraction study', *J. Appl. Phys.*, 1995, **78**, pp. 4467–4471
- 8 LIU, H.C., BUCHANAN, M., and WASILEWSKI, Z.R.: 'How good is the polarization selection rule for intersubband transitions', *Appl. Phys. Lett.*, 1998, **72**, pp. 1682–1684
- 9 YUH, P.F., and WANG, K.L.: 'Optical transitions in a step quantum well', *J. Appl. Phys.*, 1989, **65**, pp. 4377–4381

## Well-driven floating gate transistors

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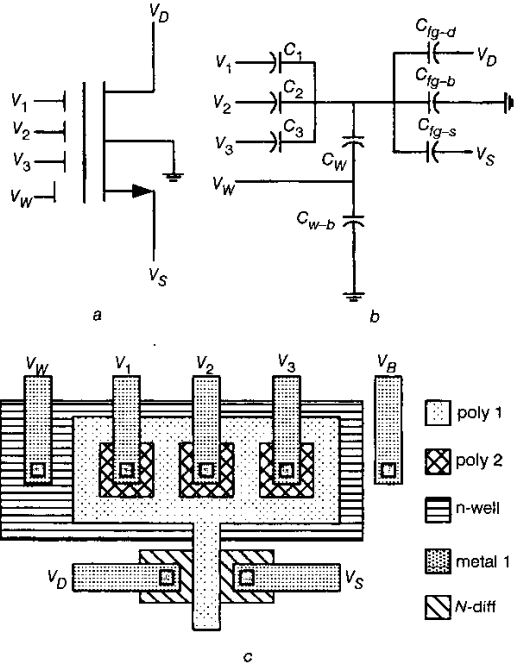
A new layout structure for floating gate MOS devices on top of an isolating  $n$ -well is proposed. The well provides the floating device with noise isolation from the substrate and can also be used as an additional input for threshold voltage control or signal modulation.

**Introduction:** Floating gate (FG) transistors are used in both digital and analogue circuits. In digital circuits they are the core of flash memories [1, 2]. For analogue circuits, multiple input (MI) FG MOS devices are used in low voltage applications [3], as analogue memories [4] or as translinear computing elements [5].

Traditionally, FG structures are laid out on top of the substrate. However, it is a common practice to lay out capacitors on top of a well to isolate the capacitor from substrate noise. Using this principle, we designed a MI-FGMOS transistor with a floating gate on top of an n-well.

**Floating gate device:** The FG element consists of an electrode surrounded by an insulator, with no direct electrical connection to any other conductor. The FG electrode acts as the gate of a MOSFET, which serves as the sensor transistor. The potential on the floating gate can be modified either by capacitive coupling with other conductors or by changing the charge stored on the floating gate [1].

In Fig. 1a, we show the symbol representing an MI-FGMOS transistor, which is a generalisation of a FG device with only one controlling gate. One of the most interesting characteristics of FG devices for analogue circuit design is that the drain current is a function of the weighted sum of voltages at the  $N$  controlling inputs.



**Fig. 1** MI-FGMOS transistor

a Symbol  
b Equivalent capacitive model  
c Layout  
 $V_w$  is additional well input

In Fig. 1c, we show the MI-FGMOS layout, including a well beneath the floating gate. In Fig. 1b, we show its capacitive equivalent model. The voltage at the floating gate can be expressed as

$$V_{FG} = \sum_{i=1}^N \alpha_i V_i + \alpha_w V_w + V_{EQ} \quad (1)$$

where  $\alpha_i = C_i/C_T$  is the  $i$ th coupling coefficient,  $C_i$  represents the capacitance from the  $i$ th controlling input  $V_i$  to the floating gate and  $C_T$  is the total capacitance of the floating gate. Similarly,  $\alpha_w = C_w/C_T$  is the coupling coefficient from the well input  $V_w$  to the floating gate.  $V_{EQ}$  is an equivalent voltage due to both the charges stored on the floating gate and to DC voltages at the source and drain that are capacitively coupled to the floating gate.

In weak inversion, the current in the drain terminal is

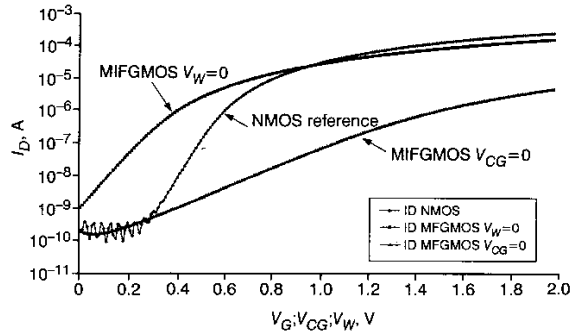
$$I_D = I_0 \exp \left\{ \frac{1}{n\phi_t} \left( \sum_{i=1}^N \alpha_i V_i + \alpha_w V_w + V_{EQ} \right) \right\} \quad (2)$$

where  $n$  is the subthreshold slope factor,  $\phi_t$  is the thermal voltage, and  $I_0$  is a constant dependent of technology and geometry [5]. The weak inversion region is more convenient to extract the subthreshold factor and thus the coupling coefficients, but the extraction methods are not limited to this level of operation.

**Measurement results:** All the measurements were performed on three-input FGMOS devices fabricated in a 0.35  $\mu\text{m}$  technology with MOSFET channel dimensions  $W=1.8 \mu\text{m}$  and  $L=0.8 \mu\text{m}$ . Each controlling input capacitor was laid out with an area of  $3.2 \mu\text{m} \times 3.2 \mu\text{m}$  resulting in  $C_i=8.8 \text{ ff}$ . The drawn area of the n-well is  $12.8 \mu\text{m} \times 5.2 \mu\text{m}$ .

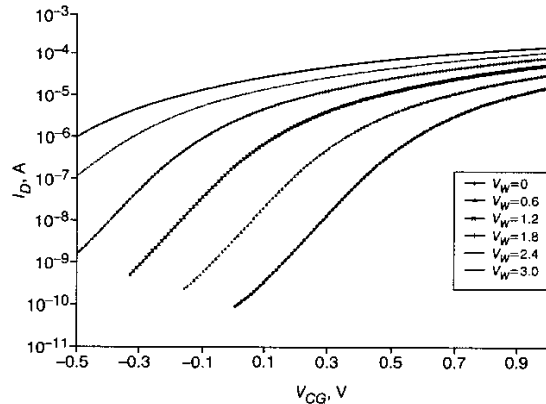
For measurement purposes we connected all controlling inputs together. From now on,  $V_{CG}$  is referred to as the controlling input and  $\alpha_{CG} = \sum_{i=1}^N C_i/C_T$ , as the total coupling coefficient associated with the controlling input.

The determination of the coupling coefficients is based on comparison of measurements taken on both the FG element and a 'dummy cell', which is a reference NMOS transistor with the same channel geometry as the FG device. To estimate  $\alpha_{CG}$  and  $\alpha_w$  we measure the equivalent subthreshold slope factors  $n$ ,  $n^{CG}$  and  $n^w$  directly from the linear portion of the drain current against voltage plots shown in Fig. 2. Referring to (2), we observe that  $n^x = n/\alpha_x$ , where  $x$  represents CG or  $w$ .



**Fig. 2**  $I_D$  against  $V_G$  (MOSFET),  $I_D$  against  $V_{CG}$  ( $V_w=0$  MI-FGMOS), and  $I_D$  against  $V_w$  ( $V_{CG}=0$  MI-FGMOS)

To extract the subthreshold slope factors from Fig. 2, we find the regions with an exponential characteristic and we obtain the values from the definition  $1/n = \phi_t d \ln(I_D)/dV_{GS}$ . The measured subthreshold slope factors obtained are  $n=1.45$ ,  $n^{CG}=2.11$  and  $n^w=5.68$ , and the corresponding coupling coefficients are  $\alpha_{CG}=0.69$  and  $\alpha_w=0.26$ .



**Fig. 3**  $I_D$  against  $V_{CG}$

In Fig. 3, we show  $I_D$  against  $V_{CG}$  plots for well voltages  $V_w$  from 0 V to 3.3 V in 0.6 V steps. The  $I_D$  against  $V_{CG}$  curve shifts to the left as  $V_w$  is increased; the result is equivalent to a modification of the effective threshold voltage  $V_T^{CG}$  seen from the controlling gate, according to

$$V_T^{CG} = \frac{1}{\alpha_{CG}} (V_T - \alpha_w V_w - V_{EQ}) \quad (3)$$

where  $V_T$  is the threshold voltage at the floating gate. We can also express the variation of the threshold voltage by

$$\Delta V_T^{CG} = -\frac{\alpha_w}{\alpha_{CG}} \Delta V_w \quad (4)$$

